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AMENDMENTS TO THE CLAIMS:

This listing of claims will replace all prior versions, and listings, of claims in the application.

Claims 1-16 (Canceled)

17. (Currently Amended) A method for manufacturing a semiconductor device comprising:

depositing a film over a substrate by repeatedly moving an a first evaporation source and a second evaporation source in an X direction while moving the substrate in a Y direction at regular intervals,

wherein the first evaporation source and the second evaporation source are provided in a same chamber in which the film is deposited.

18. (Previously Presented) The method according to claim 17, wherein the semiconductor device is incorporated into an electronic apparatus selected from the group consisting of a video camera, a digital camera, a goggle display, a navigation system, an audio reproducing apparatus, a laptop computer, a game machine, a mobile computer, a cellular phone, a portable game machine, an electronic book, and an image reproducing apparatus.

19. (Currently Amended) A method for manufacturing a semiconductor device comprising:

depositing a film over a substrate by repeatedly moving the substrate in a Y direction at regular intervals while making a movement speed of a first evaporation source in an X direction and a movement speed of a second evaporation source in the X direction different,

wherein the first evaporation source and the second evaporation source are provided in a same chamber in which the film is deposited.

20. (Previously Presented) The method according to claim 19, wherein the

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semiconductor device is incorporated into an electronic apparatus selected from the group consisting of a video camera, a digital camera, a goggle display, a navigation system, an audio reproducing apparatus, a laptop computer, a game machine, a mobile computer, a cellular phone, a portable game machine, an electronic book, and an image reproducing apparatus.

21. (Currently Amended) A method for manufacturing a semiconductor device comprising:

depositing a film over a substrate by ~~moving or~~ reciprocating an evaporation source in the X direction while moving the substrate in the Y direction at a constant speed.

22. (Previously Presented) The method according to claim 21, wherein the semiconductor device is incorporated into an electronic apparatus selected from the group consisting of a video camera, a digital camera, a goggle display, a navigation system, an audio reproducing apparatus, a laptop computer, a game machine, a mobile computer, a cellular phone, a portable game machine, an electronic book, and an image reproducing apparatus.

23. (Currently Amended) A method for manufacturing a semiconductor device comprising:

depositing an EL material over a substrate by repeatedly moving ~~an a~~ a first evaporation source and a second evaporation source in an X direction while moving the substrate in a Y direction at regular intervals,

wherein the first evaporation source and the second evaporation source are provided in a same chamber in which the EL material is deposited.

24. (Previously Presented) The method according to claim 23, wherein the semiconductor device is incorporated into an electronic apparatus selected from the group consisting of a video camera, a digital camera, a goggle display, a navigation system, an audio reproducing apparatus, a laptop computer, a game machine, a mobile computer, a cellular phone, a portable game machine, an electronic book, and an image reproducing

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apparatus.

25. (Currently Amended) A method for manufacturing a semiconductor device comprising:

depositing an EL material over a substrate by repeatedly moving the substrate in a Y direction at regular intervals while making a movement speed of a first evaporation source in an X direction and a movement speed of a second evaporation source in the X direction different,

wherein the first evaporation source and the second evaporation source are provided in a same chamber in which the EL material is deposited.

26. (Previously Presented) The method according to claim 25, wherein the semiconductor device is incorporated into an electronic apparatus selected from the group consisting of a video camera, a digital camera, a goggle display, a navigation system, an audio reproducing apparatus, a laptop computer, a game machine, a mobile computer, a cellular phone, a portable game machine, an electronic book, and an image reproducing apparatus.

27. (Currently Amended) A method for manufacturing a semiconductor device comprising:

depositing an EL material over a substrate by ~~moving or~~ reciprocating an evaporation source in the X direction while moving the substrate in the Y direction at a constant speed.

28. (Previously Presented) The method according to claim 27, wherein the semiconductor device is incorporated into an electronic apparatus selected from the group consisting of a video camera, a digital camera, a goggle display, a navigation system, an audio reproducing apparatus, a laptop computer, a game machine, a mobile computer, a cellular phone, a portable game machine, an electronic book, and an image reproducing apparatus.

29. (New) The method according to claim 17, wherein at least one of the first

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evaporation source and the second evaporation source includes at least two crucibles arranged in the X direction.

30. (New) The method according to claim 19, wherein at least one of the first evaporation source and the second evaporation source includes at least two crucibles arranged in the X direction.

31. (New) The method according to claim 21, wherein the evaporation source includes at least two crucibles arranged in the X direction.

32. (New) The method according to claim 23, wherein at least one of the first evaporation source and the second evaporation source includes at least two crucibles arranged in the X direction.

33. (New) The method according to claim 25, wherein at least one of the first evaporation source and the second evaporation source includes at least two crucibles arranged in the X direction.

34. (New) The method according to claim 27, wherein the evaporation source includes at least two crucibles arranged in the X direction.

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